REMARKS/ARGUMENTS

Claim 71 has been amended, and claims 102-109 are newly added. Claims 71-88 and 102-109 are now pending in the application. Applicants respectfully request reexamination and reconsideration of the application.

Initially, Applicants thank the Examiner for his time and the courtesy shown to Applicants during a recent in-person discussion with the Examiner regarding the pending claims. As discussed below, Applicants have amended claim 71 as was suggested during the interview to include the requirement that "said shape of said surface of said first substrate and said shape of said surface of said second substrate are independently adjustable." As was discussed at the interview, the prior art of record does not teach or suggest a plurality of substrates with probes in which shapes of the substrates are independently adjustable.

More specifically, claims 71-88 were rejected under 35 USC § 103(a) as obvious in view of US Patent No. 4,758,785 to Rath ("Rath"). To the extent the rejection is premised on dividing Rath's film probe 16 into sections and deeming each section a different substrate, such "substrates," because they are part of the same overall structure, namely Rath's film probe 16, are not independently adjustable. Nor does Rath include any teaching or suggestion that would lead a person of ordinary skill in the field to modify Rath to include two independently adjustable film probes 16. Indeed, there would be no advantage in doing so and therefore no incentive to do so. For all of the foregoing reasons, Rath fails to teach or suggest claim 71.

Claims 72-88 depend from claim 71 and are therefore also patentable over Rath.

Moreover, claims 72-88 recite additional features that are not taught or suggested by Rath.

For example, claim 76—which was not addressed in the Office Action—states that the shape of the first substrate is adjusted *without contacting* the device(s) to be tested, and claim 77 similarly states that the shape of the second substrate is adjusted without contacting the device(s) to be tested. According to the Office Action, the act of pressing Rath's wafer 79 (which is the device to be tested in Rath) against pads 18 changes the shape of film probe 16. No other act or method of changing the shape of film probe 16 is identified in the Office Action or taught or suggested by Rath. Rath thus fails to teach or suggest the requirements of claim 76 and 77.

As another example, claims 80-84 include a requirement of multiple actuators. Rath discloses only one actuator: chuck 76. Moreover, there is no suggestion or motivation and no reason to add additional actuators to Rath. Again, the use of multiple actuators in claims 80-84

is not a mere duplication of parts. Rather, the use of multiple actuators allows greater control over the shape of the substrates to which the probes are attached. Rath provides no such advantage. Thus, Rath fails to teach or suggest claims 80-84.

As yet another example, claims 87 and 88—which were not addressed in the Office Action—state that the probes are elongate and resilient and provide individual compliance with respect to terminals of the device to be tested. Rath's pads 18 (which were equated with the probes of the claims of the instant application) are not elongate or resilient and do not provide individual compliance with respect to wafer 79. Nor would there be any reason to so modify Rath's pads 18. Therefore, Rath fails to anticipate or render obvious claims 87 and 88.

New claims 102-109 also recite additional features that are not taught or suggested by Rath.

For example, new claim 102 states that the actuator recited in claim 78 applies a selected force directly to a surface of the first substrate that is opposite the surface to which the first probes are attached. Claim 104 similarly requires that the plurality of forces recited in claim 75 are applied to a surface of the first substrate that is opposite the surface to which the probes are attached. In contrast, the only application of force taught or suggested by Rath arises from the pressing of wafer 79 against pads 18. Necessarily, such a force can only be applied directly to pads 18. Rath therefore does not anticipate or render obvious claims 102 or 104.

Claim 103 states that the actuator of claim 78 does not move the device(s) to be tested, and claim 105 states that the forces of claim 75 are not applied through the device(s) to be tested. Again, in Rath the only actuator is chuck 76 and it moves wafer 79 (which is the device to be tested in Rath). Moreover, all of the push and pull forces described in the Office Action arise from pressing of wafer 79 against pads 18. The forces described in the Office Action are therefore necessarily applied through wafer 79. Rath thus fails to teach or suggest the requirements of claims 103 and 105.

Claim 106 states that at least five forces are applied to at least five regions of the first substrate. Typically, the greater the number of forces applied to different regions of the substrate the greater the control over the shape of the substrate. Rath does not teach or suggest the features of claim 106.

Claim 107 states that the first and second substrates are disposed such that their respective probes form one array of probes for contacting the device(s) to be tested. Claim 106

further states that the "step of adjusting a planarity of contact portions of said probes comprises planarizing said contact portions of said entire array of probes." As acknowledged in the Office Action, Rath does not teach or suggest utilizing more than one substrate with probes and therefore necessarily does not teach or suggest forming one array of probes comprising probes attached to multiple substrates, nor does Rath teach or suggest planarizing such an array of probes by adjusting the shapes of the substrates to which the probes are attached. Rath thus fails to teach or suggest the requirements of claim 107.

Claim 108 states that the step of adjusting the shape of a surface of the first substrate includes imparting a curvature to the surface. Rath does not teach or suggest imparting a curvature to film probe 16.

As suggested by the Examiner, claim 109 states that the first substrate and the second substrate are part of a probe card assembly, which also includes a reference structure. The shapes of the first substrate and the second substrate are adjusted relative to the reference substrate. Rath does not teach or suggest such features.

For all of the above reasons, Applicants respectfully assert that all of the claims are in condition for allowance. Applicants therefore request withdrawal of the rejection and allowance of the application. If at any time the Examiner believes that a discussion with Applicants' attorney would be helpful, the Examiner is invited to contact the undersigned at (801) 323-5934.

Respectfully submitted,

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